Suppl	lemental
Notice o	of Allowability

Application No.	Applicant(s)	_
10/045,653	VYVODA ET AL.	
Examiner	Art Unit	
Vikki H. Trinh	2814	

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	Vikki H. Trinh	2814	L
The MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication GHTS. This application is subject to	olication. If not include will be mailed in due	ed course. THIS
1. This communication is responsive to <u>05/04/05</u> .			
2. ⊠ The allowed claim(s) is/are <u>1-5, 7-8,12-14,16 and 19</u> .			
3. X The drawings filed on <u>07 November 2001</u> are accepted by	the Examiner.		
4. Acknowledgment is made of a claim for foreign priority un a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" on the delow. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be submited in INFORMAL PATENT APPLICATION (PTO-152) which give (a) including changes required by the Notice of Draftsperson 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the certification of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the depose attached Examiner's comment regarding REQUIREMENT For the composition of the compo	been received. been received in Application No cuments have been received in this report of this communication to file a reply of ENT of this application. Itted. Note the attached EXAMINER' is reason(s) why the oath or declarate to be submitted. It be submitted. It has application in the Office of the comment of the Office	national stage applicate complying with the reconstruction of the front (not the li).	quirements OTICE OF
Attachment(s) 1. ☐ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/06) Paper No./Mail Date 11/2/01 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	5. ☐ Notice of Informal Pa 6. ☐ Interview Summary (Paper No./Mail Date 7. ☐ Examiner's Amendm 8. ☒ Examiner's Stateme 9. ☒ Other ☐ ☐ ☐ ☐ ☐ ☐	(PTO-413), e nent/Comment nt of Reasons for Allo	,

Allowable Subject Matter

1. Claims 1-5, 7-8, 12-14, 16, and 19 are allowed.

2. The following is an examiner's statement of reasons for allowance: The prior art of record does not disclose or fairly suggest either in singly or in combination a method for making a semiconductor device having the steps of providing a capping structure over the insulating layer; annealing the resulting structure, wherein a portion of the metal structure has a width greater than 1 micron, wherein the capping and annealing prevents peeling of the metal structure

when heated; and other steps in the claims.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Vikki Trinh whose telephone number is (571) 272-1719. The Examiner can normally be reached from Monday-Friday, 9:00 AM - 5:30 PM Eastern Time. If attempts to reach the examiner by telephone are unsuccessful, the Examiner's supervisor, Mr. Wael Fahmy, can be reached at (571) 272-1705. The office fax number is 703-872-9306.

Any request for information regarding to the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Also, status information for

published applications may be obtained from either Private PAIR or Public Pair. In addition, status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. If you have questions pertaining to the Private PAIR system, please contact the Electronic Business Center (EBC) at 866-217-9197 (toll free).

Lastly, paper copies of cited U.S. patents and U.S. patent application publications will cease to be mailed to applicants with Office actions as of June 2004. Paper copies of foreign patents and non-patent literature will continue to be included with office actions. These cited U.S. patents and patent application publications are available for download via the Office's PAIR. As an alternate source, all U.S. patents and patent application publications are available on the USPTO web site (www.uspto.gov), from the Office of Public Records and from commercial sources. Applicants are referred to the Electronic Business Center (EBC) at http://www.uspto.gov/ebc/index.html or 1-866-217-9197 for information on this policy. Requests to restart a period for response due to a missing U.S. patent or patent application publications will not be granted.

Vikki Trinh, Patent Examiner AU 2814